

**METHOD OF FORMING MICROSTRUCTURES ON A SUBSTRATE AND A
MICROSTRUCTURED ASSEMBLY USED FOR SAME**

Abstract

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A method of forming microstructures on a substrate is disclosed. A microstructured assembly that may be used in the method for forming microstructures on a substrate is also disclosed. The methods and assemblies of the present disclosure can reduce the amount of air entrapped in barrier ribs formed on substrates used in Plasma Display devices.

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